Electronic Patent Application Fee Transmittal							
Application Number:	10583976						
Filing Date:							
Title of Invention:	Method for setting plasma chamber having an adaptive plasma source, plasma etching method using the same and manufacturing method for adaptive plasma source						
First Named Inventor:	Yeong Su Song						
Filer:	Sungho Hong/Anita Coughlan						
Attorney Docket Number:	4913-0001						
Filed as Small Entity							
U.S. National Stage under 35 USC 371 Filing Fees							
Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)			
Basic Filing:		,					
Pages:							
Claims:							
Miscellaneous-Filing:							
Oath/decl > 30 mo. from priority date	2617	1	65	65			
Petition:							
Patent-Appeals-and-Interference:							
Post-Allowance-and-Post-Issuance:							
Extension-of-Time:							

Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Miscellaneous:				
	Total in USD (\$)			65